Abstracts

Picosecond Reflectometry Technique for On-Chip Characterization of Millimeter-Wave Semiconductor Devices

C. Rauscher. "Picosecond Reflectometry Technique for On-Chip Characterization of Millimeter-Wave Semiconductor Devices." 1987 MTT-S International Microwave Symposium Digest 87.2 (1987 Vol. II [MWSYM]): 881-884.

A multi-sampler reflectometer technique is described for on-chip characterization of semiconductor devices at millimeter-wave frequencies. Focus is on enhancing measurement accuracy and frequency band coverage by augmenting photoconductive circuit elements, which perform signal generation and sampler functions, with pulse-shaping and impedance-matching networks. The approach is illustrated with a GaAs 150 GHz bandwidth example.

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